

PATENT



Attorney Docket No.: A-68359-1 (475852-7)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Gerard S. MOLONEY

Serial No. 10/027,935

Filed: December 21, 2001

For: APPARATUS AND METHOD  
FOR CHEMICAL-MECHANICAL  
POLISHING (CMP) HEAD  
HAVING DIRECT PNEUMATIC  
WAFER POLISHING PRESSURE

Group Art Unit: 3724

Examiner: ELEY, Timothy V.

Confirmation No.: 2631

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence and its listed enclosures is being deposited with the United States Postal Service as First Class Mail addressed to Commissioner for Patents; P.O. Box 1450; Alexandria, VA 22313-1450 on August 31, 2005.

Signed Vikki Athen  
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